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**INFORMATION DISCLOSURE STATEMENT
BY APPLICANT**

Applicant: BASELMANS et al.

Appln. No.: TO BE ASSIGNED

Filing Date: February 12, 2002

Examiner: UNKNOWN

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Date: February 12, 2002

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of

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U.S. PATENT DOCUMENTS

Examiner's Initials*		Document Number	Date MM/YYYY	Name (Family Name of First Inventor)	Class	Sub Class	Filing Date (if appropriate)
HW	AR	6,100,978	08/2000	Naulleau et al.	356	354	
HW	BR	6,118,535	09/2000	Goldberg et al.	356	354	
	CR						
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	ER						
	FR						
	GR						
	HR						
	IR						
	JR						
	KR						
	LR						
	MR						

FOREIGN PATENT DOCUMENTS

		Document Number	Date MM/YYYY	Country	Inventor Name		English Abstract	Translation Readily Available
							Enclosed	No
	NR							
	OR							
	PR							
	QR							
	RR							
	SR							
	TR							

OTHER (Including in this order Author, Title, Periodical Name, Date, Pertinent Pages, etc.)

HW	UR	Goldberg et al., "High-accuracy interferometry of extreme ultraviolet lithographic optical systems," <i>J. Vac. Sci. Technol. B</i> 16(6):3435-3439 (1998)			
	VR	Braat et al., "Improved Ronchi test with extended source," <i>J. Opt. Soc. Am. A</i> 16(1):131-140 (1999)			
	WR	Venkataraman, et al., "Aberrations of steppers using Phase Shifting Point Diffraction Interferometry," In <i>Optical Microlithography XIII</i> , Christopher J. Proglar, Ed., Proceedings of SPIE 4000:1245-1249 (2000)			
HW	XR	A copy of the European Search Report dated August 24, 2001 issued in the corresponding European application No. EP 01 30 1283			
	YR				
	ZR				

Examiner

Nguyen, Henry Hung

Date Considered:

3/13/2003

*EXAMINER: Initial if citation considered, whether or not citation is in conformance with MPEP § 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.